Advanced Imaging Core Facility (AICF)
Skolkovo Institute of Science and Technology (Skoltech)

30c1 Bolshoi Blvd
Innovation Center "Skolkovo"
Moscow, Russia
121205

advancedimaging@skoltech.ru

APPROVED:
Head of AICF
Y. Shakhova

Head of Shared Facilities Office
A. Denisov

valid as of date: 22/04/2020

Tariffs

For external customers

№ p/p	Equipment	Access type*	Price, RUB without VAT
1	Transmission electron microscope with probecorrector **Titan Themis Z**	per hour with AICF operator	13 524
2	Scanning electron microscope with low-vaccuum mode **Quattro S SEM**	per hour with AICF operator	5 253
		per hour without AICF operator**	2 838
		per day of training course	61 341
3	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	per hour with AICF operator	10 264

Typical services provided by AICF

№ p/p	Typical services	Used equipment	Unit of measurement, sample	Price***, RUB without VAT
1	Particle morphology investigation	Scanning electron microscope with low-vaccuum mode **Quattro S SEM**	1 sample	8 758
2	Surface morphology investigation of the sample, if necessary, the use of a backscattered electron detector	Scanning electron microscope with low-vaccuum mode **Quattro S SEM**	1 sample	11 930
3	Investigation of the elemental composition of the sample (by 5 points)	Scanning electron microscope with low-vaccuum mode **Quattro S SEM**	1 sample	8 758
4	Investigation of the elemental composition of the	Scanning electron	1 sample	15 101

	sample (mapping of 3 areas)	microscope with low-vaccuum mode **Quattro S SEM**		
5	Particle morphology investigation	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	1 sample	14 809
6	Surface morphology investigation of the sample, if necessary, the use of a backscattered electron detector	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	1 sample	21 006
7	Investigation of the elemental composition of the sample (by 5 points)	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	1 sample	23 421
8	Investigation of the elemental composition of the sample (mapping of 3 areas)	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	1 sample	42 011
9	Preparation and visualization of cross-section	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	1 sample	23 421
10	Preparation of lamella for TEM investigation	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	1 sample	49 575
11	Preparation of lamella for TEM investigation at the given point in accordance with Customer request	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	1 sample	61 969
12	Investigation of multilayer structures in the STEM mode, including investigation of the elemental composition of the sample (along the line)	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	1 sample	42 011

13	Investigation of the crystallographic orientation of the grain structure (EBSD)	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	1 sample	Договорная, зависит от ТЗ
14	Investigation of the morphology of nanoparticles in TEM or STEM modes	Transmission electron microscope with probecorrector **Titan Themis Z**	1 sample	37 491
15	Investigation of the grain structure of a sample including determination of dislocation density	Transmission electron microscope with probecorrector **Titan Themis Z**	1 sample	74 981
16	Investigation of the crystal structure of a sample using electron diffraction	Transmission electron microscope with probecorrector **Titan Themis Z**	1 sample	79 911
17	Visualization of the crystal structure of the sample in high resolution TEM or STEM	Transmission electron microscope with probecorrector **Titan Themis Z**	1 sample	91 311
18	Solution of the crystal structure of a sample using electron diffraction tomography	Transmission electron microscope with probecorrector **Titan Themis Z**	1 sample	166 867
19	Investigation of the elemental composition of the sample using energy dispersive X-ray spectroscopy (EDX) (mapping of 3 areas)	Transmission electron microscope with probecorrector **Titan Themis Z**	1 sample	53 821
20	Mapping of the elemental composition of the sample using energy dispersive x-ray spectroscopy (EDX) with atomic resolution (mapping of 3 areas)	Transmission electron microscope with probecorrector **Titan Themis Z**	1 sample	102 811
21	Investigation of the elemental composition of the sample, including light elements, using electron energy loss spectroscopy (EELS) (spectra acquisition at 5 points)	Transmission electron microscope with probecorrector	1 sample	74 981

		Titan Themis Z		
22	Mapping of the elemental composition of the sample, including light elements, using electron energy loss spectroscopy (EELS) in the STEM mode (mapping of 3 areas)	Transmission electron microscope with probecorrector **Titan Themis Z**	1 sample	91 311
23	Visualization of nanoparticles using electron tomography	Transmission electron microscope with probecorrector **Titan Themis Z**	1 sample	166 867
24	Visualization of multilayer structures (heterostructures) with atomic resolution	Transmission electron microscope with probecorrector **Titan Themis Z**	1 sample	91 311

For internal customers****

№ p/p	Equipment	Access type*	Price, RUB without VAT
1	Transmission electron microscope with probecorrector **Titan Themis Z**	per hour with AICF operator	8 207
		per hour without AICF operator**	6 207
2	Scanning electron microscope with low-vaccuum mode **Quattro S SEM**	per hour with AICF operator	3 194
		per hour without AICF operator**	1 194
		per day of training course	9 554
3	Dual beam scanning electron microscope **Helios G4 UXe PFIB/SEM**	per hour with AICF operator	5 943
		per hour without AICF operator**	3 943

Prices are indicated for equipment rent only; interpretation of results and preparation of reports are charged separately.

Duration and contents of the training are determined based on the trainee's level.

** Access to sample preparation equipment (except listed above) is not charged (free). However, in case operator assistance is required, a rate of 2 300 RUB / hour will be applied*

*** Access granted only after completing a corresponding training course*

**** The cost is indicated without taking into account the sample preparation*

***** Includes Skoltech members, Skoltech start-ups and participants of Skolkovo ecosystem*